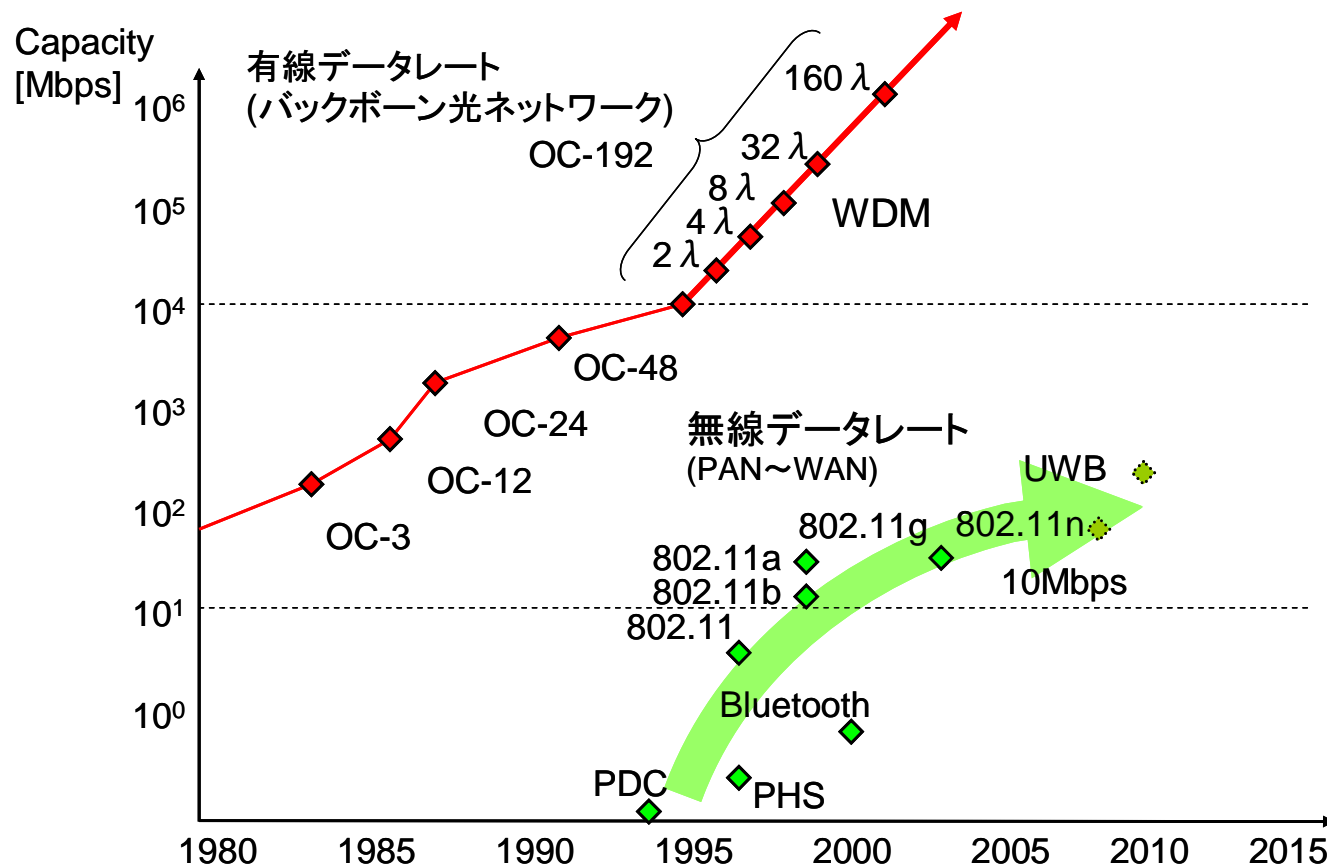


ダミーフィルを考慮した 60GHz CMOS増幅器設計

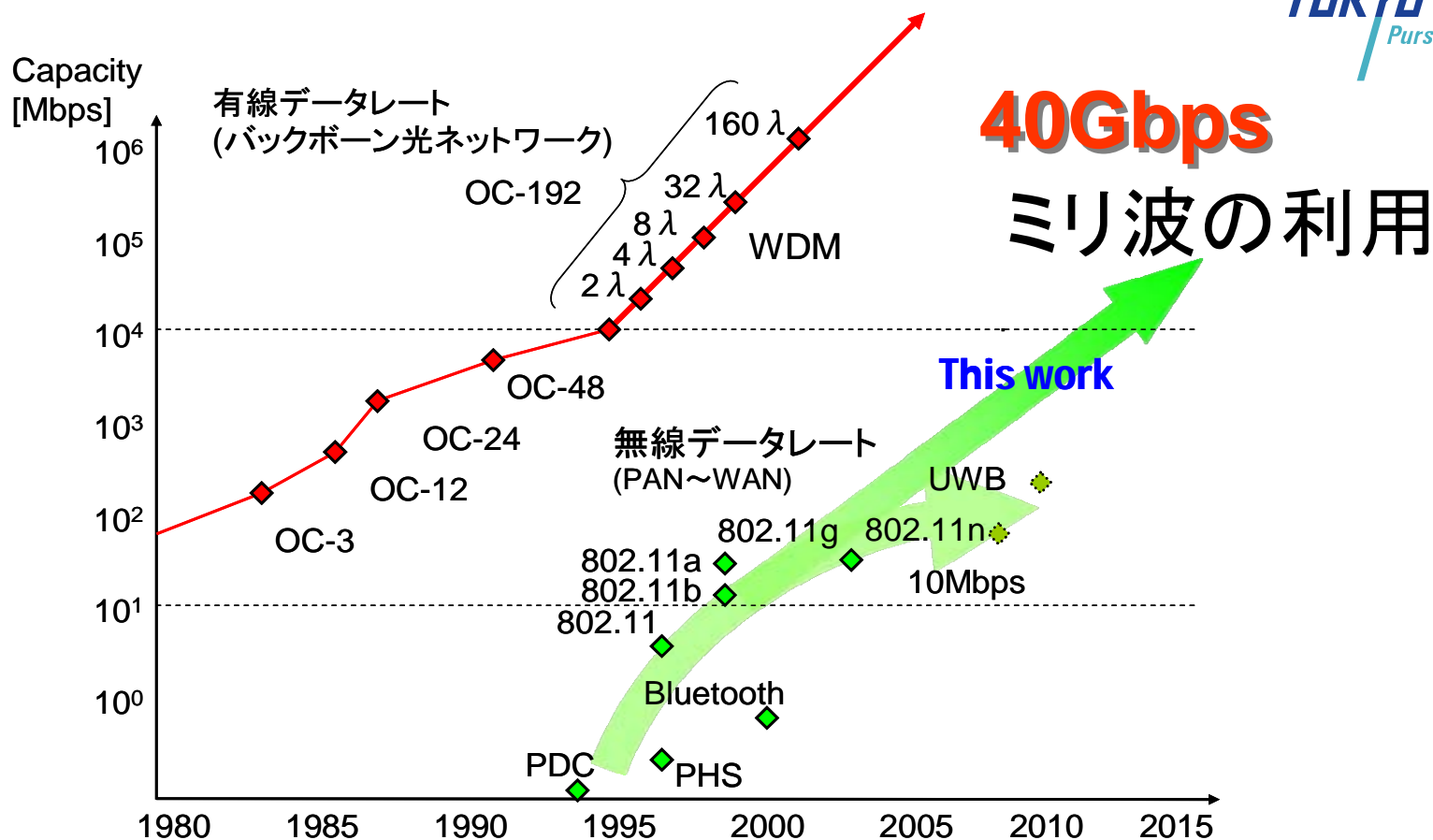
○岡田 健一, 高山 直輝, 松下 幸太,
李 寧, 伊藤 彰吾, 松澤 昭

東京工業大学

2009/11/10



コンテンツの情報量 \propto LSIの性能
 有線の通信速度 \propto LSIの性能
 無線の通信速度 \propto 周波数帯域



コンテンツの情報量 \propto LSIの性能
 有線の通信速度 \propto LSIの性能
 無線の通信速度 \propto 周波数帯域

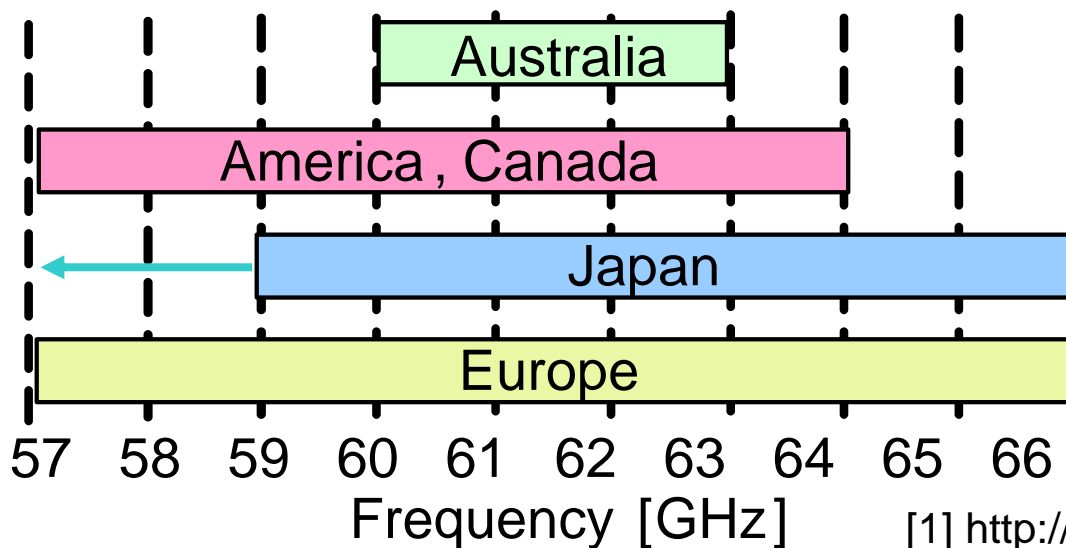
➡ ミリ波による
超高速無線通信

60GHz帯で、最大9GHz帯域の利用が可能

あくまでも机上の空論ですが...

carrier	57GHz-66GHz	
channel-BW	8640MHz(4ch)	
symbol rate	6912Mbps	
変調	64QAM	= 約40Gbps

60GHz unlicensed band



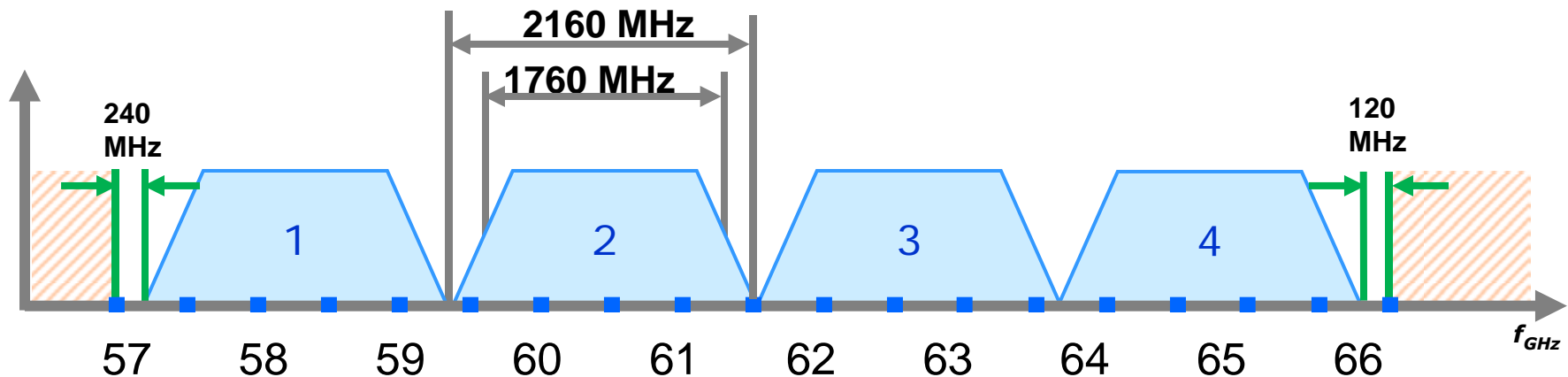
- 9GHz-BW around 60GHz
 - ➡ Several-Gbps wireless communication
- Use of CMOS process
 - ➡ Fab. cost is very important to generalize it.
RF&BB mixed chip can be realized.

60GHz channel plan

IEEE802.15.3c

Ref: IEEE 802.15-09-192-003c with draft doc.

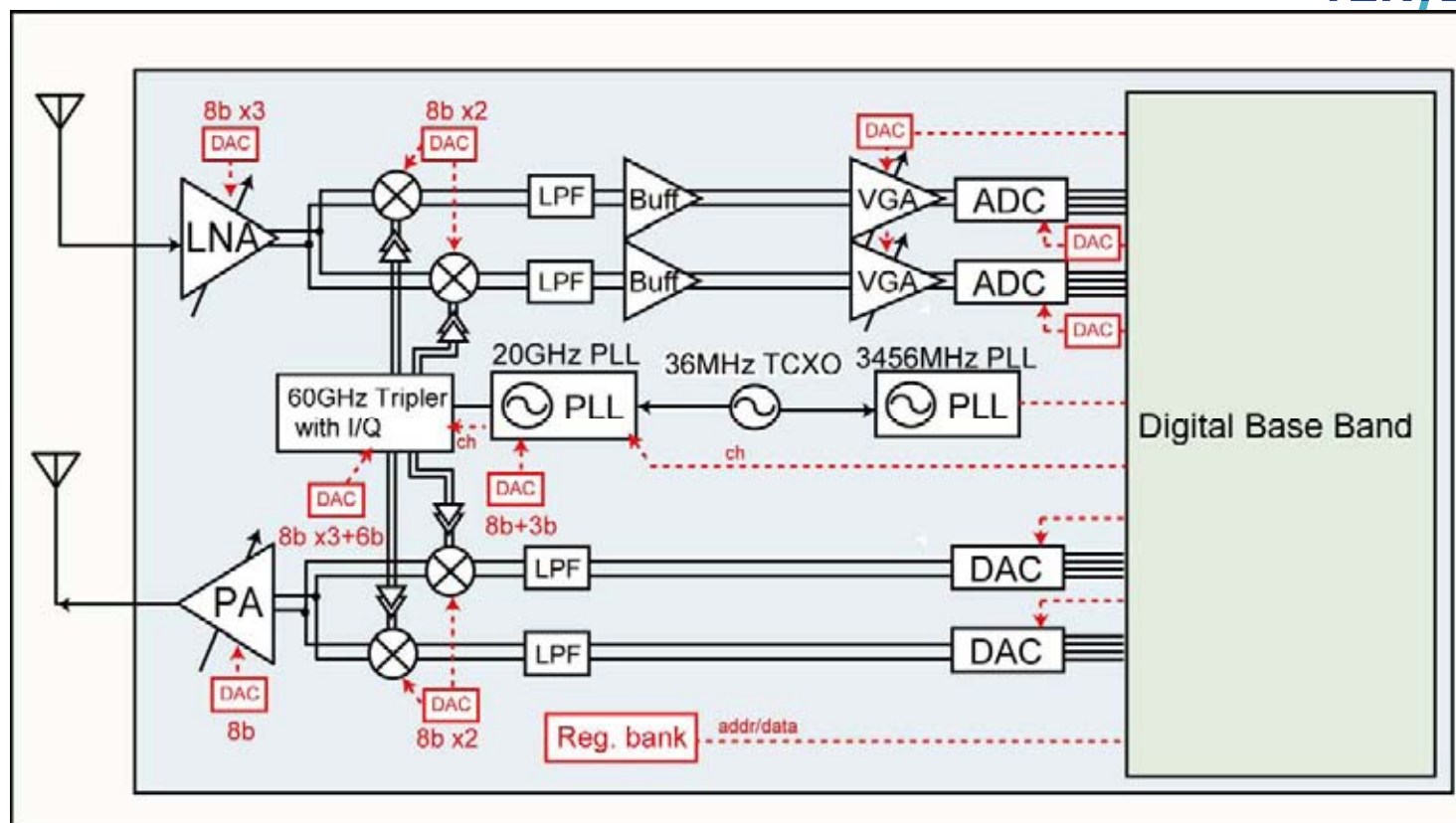
Channel Number	Low Freq. (GHz)	Center Freq. (GHz)	High Freq. (GHz)	Nyquist BW (MHz)	Roll-Off Factor
A1	57.240	58.320	59.400	1760	0.227
A2	59.400	60.480	61.560	1760	0.227
A3	61.560	62.640	63.720	1760	0.227
A4	63.720	64.800	65.880	1760	0.227



4 channel of 2.16GHz-BW

- One unified MAC
- Three PHYs optimized for respective and specific market segments
 - **Single carrier (SC) PHY**
 - low complexity, low power consumption and low cost
 - handheld mobile applications
 - **High speed interface (HSI) PHY - OFDM**
 - low latency bi-directional data communications
 - PC peripherals
 - **AV PHY - OFDM**
 - optimized for high speed uncompressed video transmission
 - Audio/visual consumer electronics (CE) applications

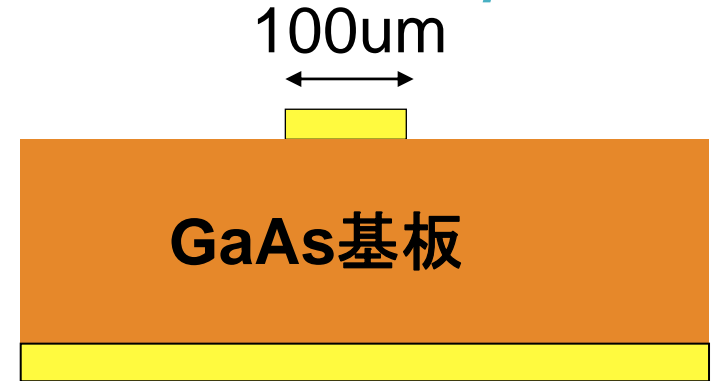
Our target



60GHz 2.16GHz-**full 4ch direct-conversion** by **CMOS**
QPSK 3Gbps & **16QAM 6Gbps & 64QAM 9Gbps**
IEEE 802.15.3c conformance

Dynamic power management: <300mW for RF front-end

- **そもそも素子性能が低い**
 - トランジスタの利得が低い
 - マッチング用素子の損失が大きい (TL, Inductor等)
- **モデリング・シミュレーション精度が低い**
 - 測定精度
 - レイアウト精度 (微小な寄生容量でも致命的に)
- **素子モデルがない**
 - ファウンダリからのPDKはせいぜい20GHzまで
- **ダミーメタル (密度ルール)**



裏面がGNDでない

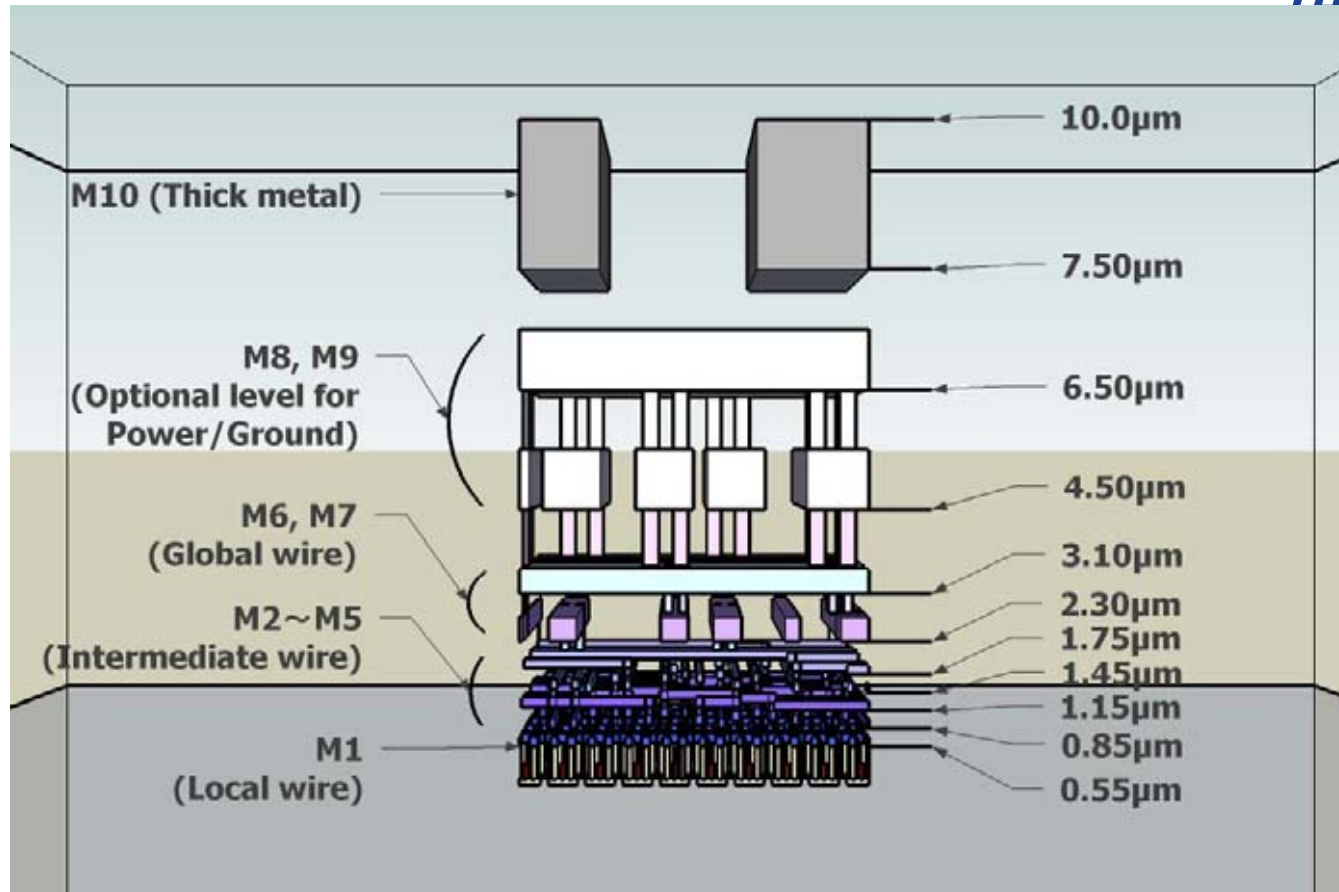
配線幅 10um

配線厚 1~2um (最大)

誘電体厚 ~5um

導体損 + 基板による渦電流損

⇒ **0.5~1dB/mm @60GHz**

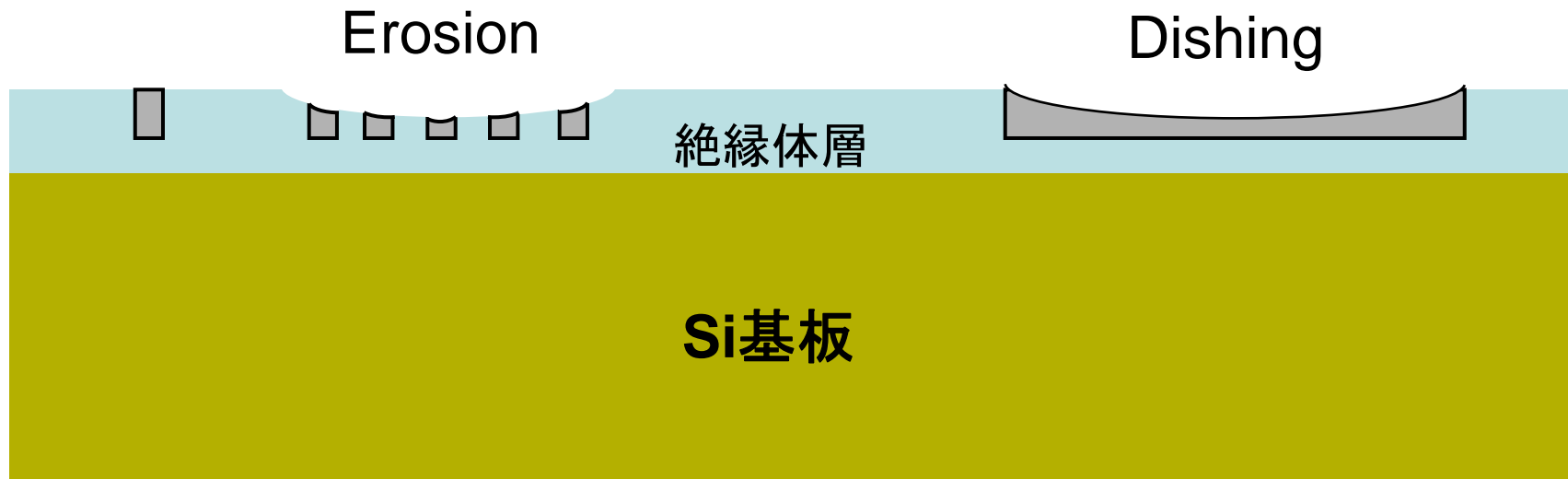


<http://www.tamaru.kuee.kyoto-u.ac.jp/~tsuchiya/LSI-3D-CG.html>

- ・層によって誘電率が異なる
- ・Cu配線は、バリアメタルにより、外辺部分が高抵抗

一層ごとに配線を削り、平滑化する

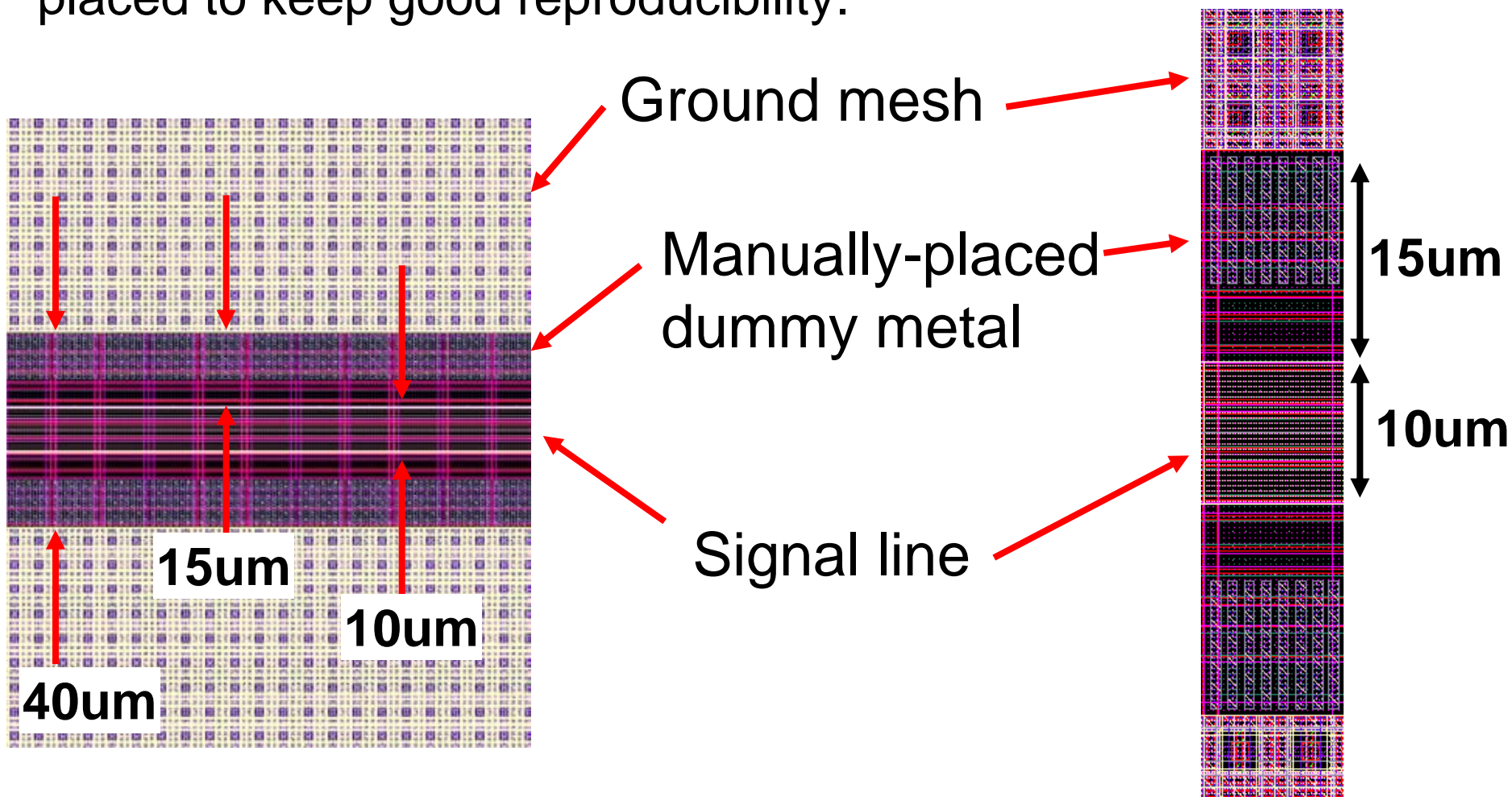
CMP (Chemical Mechanical Polishing/Planarization)



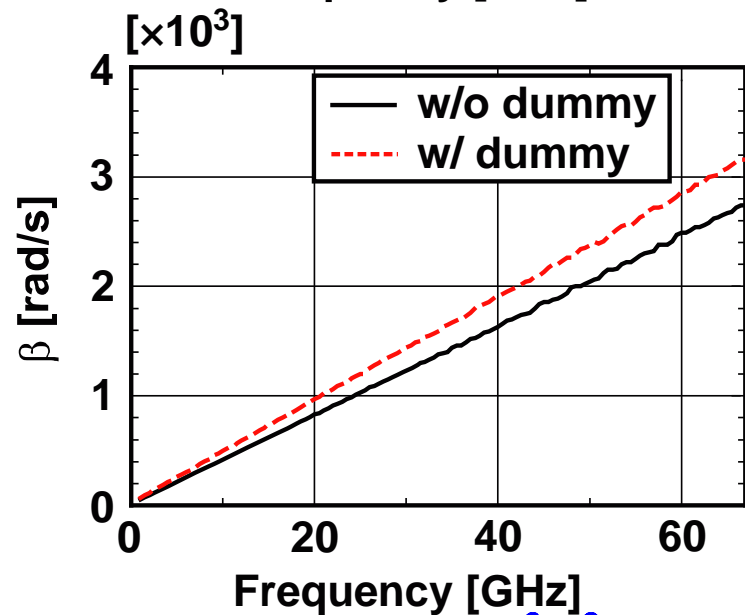
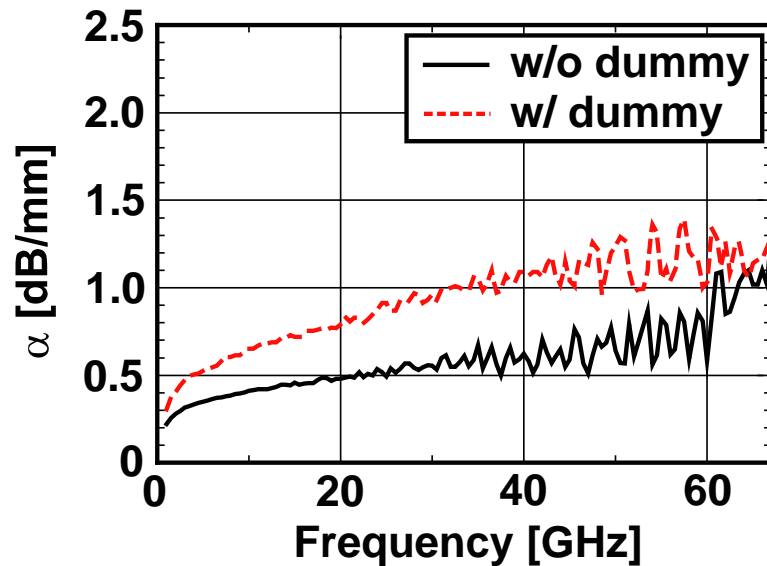
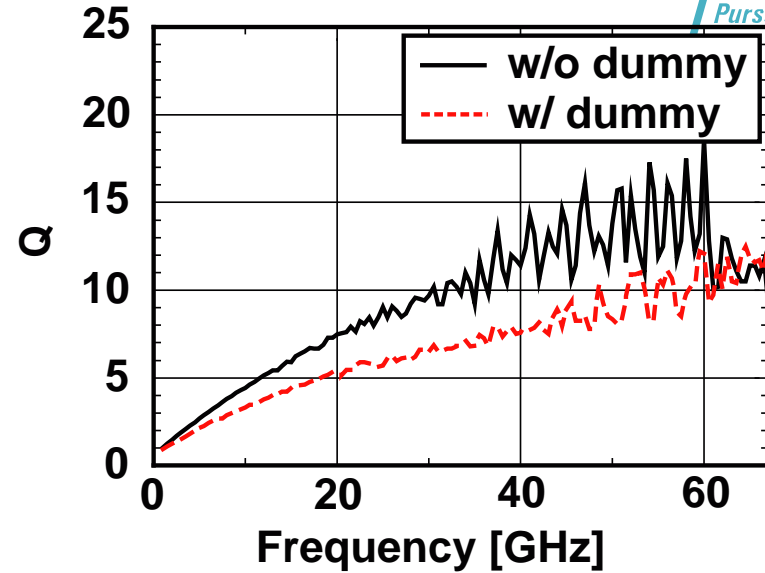
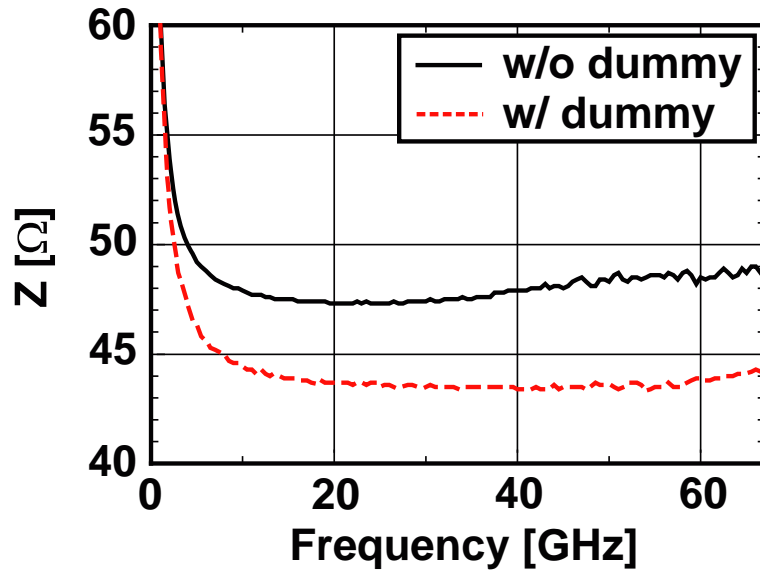
CMPによる削れムラを減らすために、
ダミー配線を入れて、配線密度を一定にする必要がある。

Dummy metal in TL

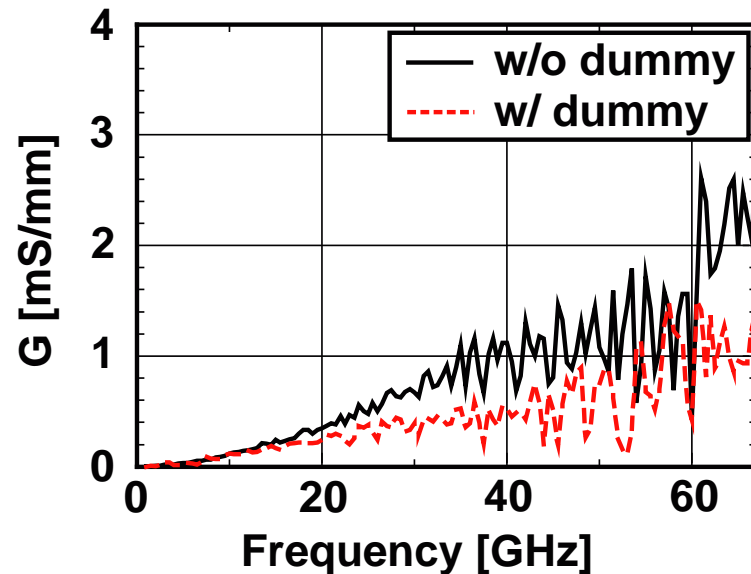
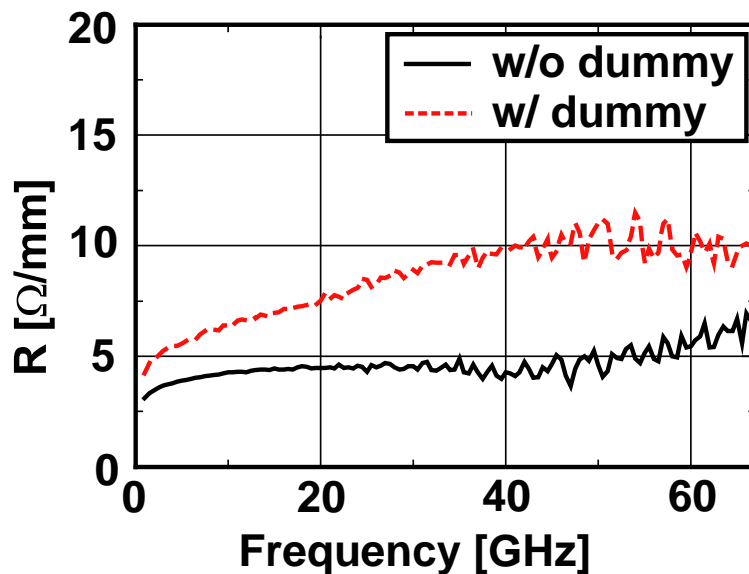
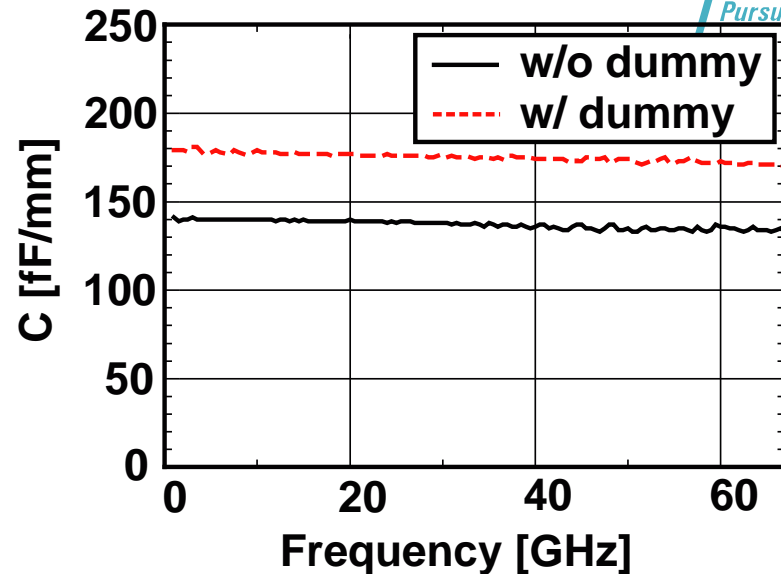
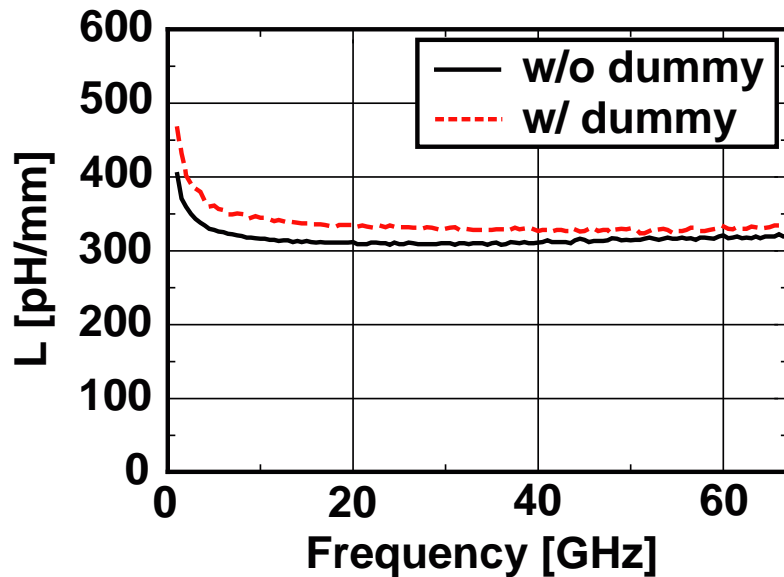
To avoid random production of dummy metal, it is manually placed to keep good reproducibility.



ダミー入り伝送線路の特性1



ダミー入り伝送線路の特性2



ダミー手置き \Rightarrow ダミー自動生成の影響

Z: 10%程度低下

Q: 15 \Rightarrow 10

α : 0.7dB/mm \Rightarrow 1.2dB/mm

β : 10%程度増加

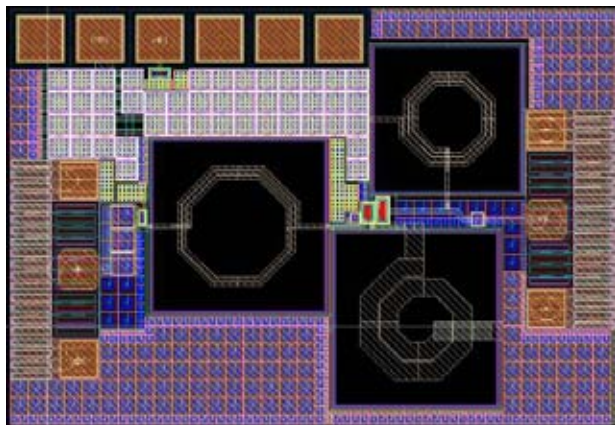
L: ほぼ変化なし

C: 20%程度増加

R: 50%増加(測定誤差大)

G: 40%減少(測定誤差大)

- **伝送線路によるマッチング**
寄生素子の排除
- **タイルベースレイアウト**
厳密にレイアウトとモデルを一致させる
ダミーメタルの手置き
- **実測に基づくIn-house PDK**
実測ベースの分岐・曲げモデル
分布デカップリングモデル
伝送線路によるマッチング (vs インダクタ)
固定寸法トランジスタモデル



Inductor @ 5GHz



Transmission line @ 60GHz

- 引き出し線、素子間配線の影響 (寄生インダクタンス)
- 寄生容量の影響の排除
- スケーラブル (長さ調整)

Tile-based layout

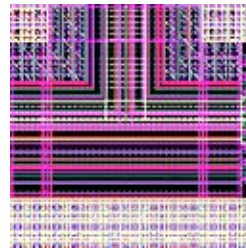
Each component is previously measured and modeled.
The same layout is utilized to maintain modeling accuracy.



RF PAD

2009/11/10

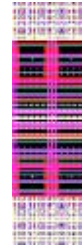
5mm pitch



T-Junction



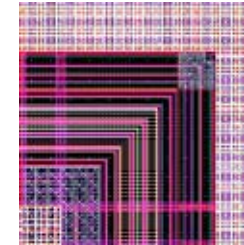
Tr



TL



C



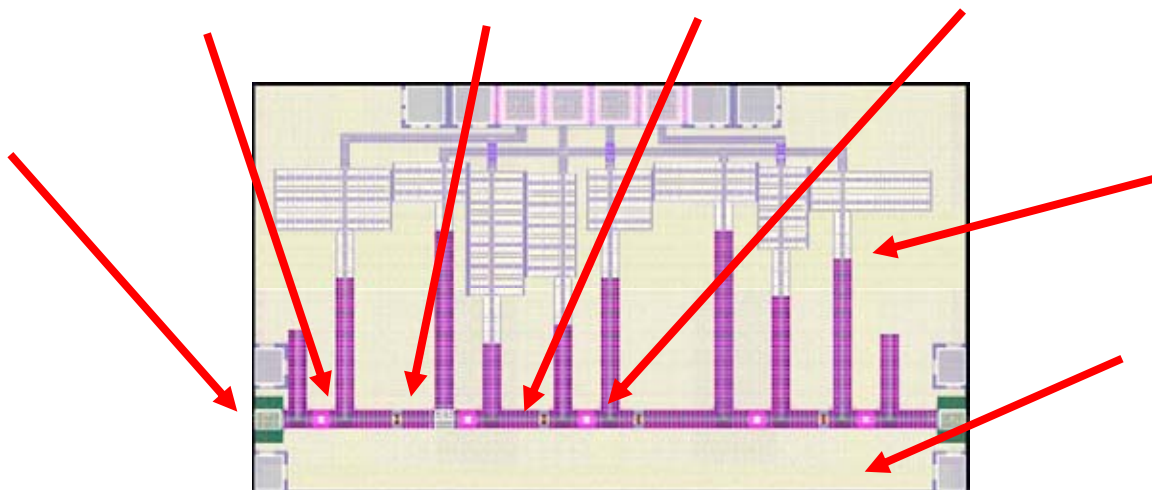
L-Bend



MIM TL



GND-Tile



See inside of top_pdk and top_meas.
top_pdk top_meas

To see simulation results, copy top_pdk.dds and top_meas.dds.

PDK

Nominal	Fast	Slow
1.0F/um ² Min Cap	c_min15f	
1.0F/um ² Min Cap	c_min5f	
1.2v HS NFETs	nch_macharf	
1.2v SB NFETs	nch_sbdrf	
1.2v HS PFETs	pch_macharf	
1.2v SB PFETs	pch_sbdrf	
3.3v HS NFETs	h3_3vch_nch(N/A)	
3.3v HS PFETs	h3_3vch_pch(N/A)	
Single-mode inductors	ind_2p3_ind_0p9_stack(N/A)	
Diff inductors	inddiff_3p3_inddiff_0p9_stack(N/A)	
1.2v Resistor	rs_12	
3.3v Resistor	rs_33	
VFNF	vf_nfnf	
Unsalicided resistors	rsp_rsp_pwr_rsp_mw (520-555 OhmS/g)	
N-Salicided resistors	rsn_rsn_pwr_rsn_mw (15 OhmS/g)	
P-Salicided resistors	rsp_rsp_pwr_rsp_mw (25 OhmS/g)	

Transistor (PDK)

Resistor (PDK)

Unsalicided resistors (rsp_rsp_pwr_rsp_mw)
w<=0.5um, L<=3.0um
(520-555 OhmS/g) depending aspect ratio

N-Salicided resistors (rsn_rsn_pwr_rsn_mw)
w<=0.5um, L<=3.0um
(15 OhmS/g)

P-Salicided resistors (rsp_rsp_pwr_rsp_mw)
w<=0.5um, L<=3.0um
(25 OhmS/g)

Varactor (PDK)

v<=1.0 (Design Rule)
w<=10um, L<=10um (Design Rule)
w<=3um, L<=0.5um, of<=15 (Layout PDK)

MIM Capacitor (PDK)

c_min15f (RL) <= 103um (Design Rule)
W<=5um, L<=17um (Layout PDK)

3.3V MOS decoupling (PDK nonDFM)

h<=1 (DFM)
h<=1 (DFM)
h<=1 (DFM)
h<=1 (DFM)

model C

Capacitor (model)

MIM TL (model)

Transmission Line (model)

RF PAD (model)

60um x 40um RF PAD

DC probe (meas.)

only reliable up to 20GHz

PVT

MIM TL

TL with L/T

DC probe

RF PAD

R

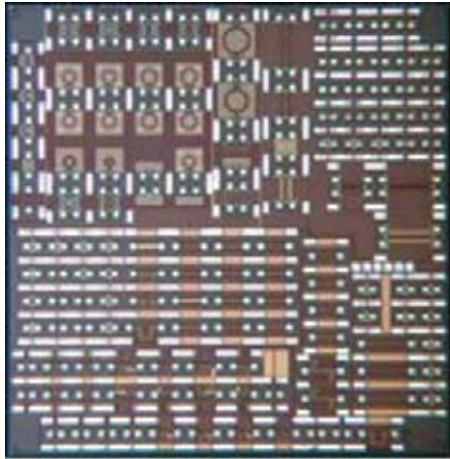
MIM

MOS cap

NMOS

PMOS

Each component is implemented as an in-house PDK for Agilent ADS.

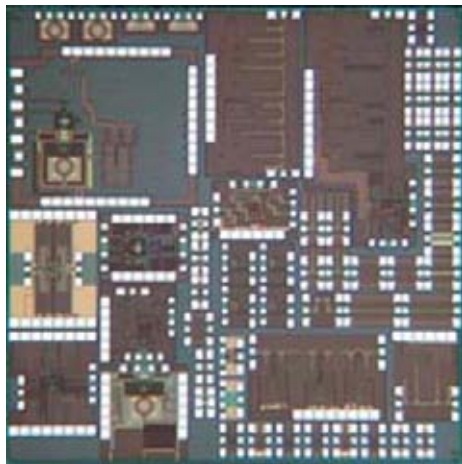


Initial T.O.

Initial T.O. for **Modeling**

- Transistors (CS, CG with various layouts)
- Transmission line (various length & Z_0)
- Branch & bend line
- Spiral inductor
- Balun
- Series capacitor
- Decoupling capacitor
- De-embedding patterns
- 1-stage amplifier for the model evaluation
- DC probe

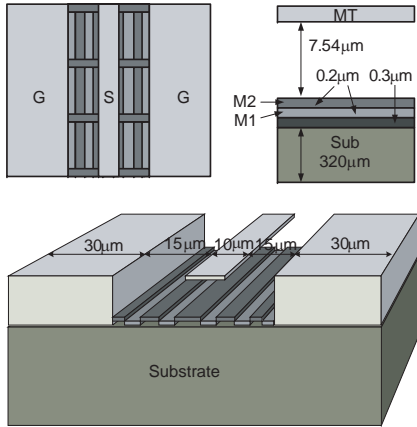
低い素子特性を可能な限り補うため、
モデリングは非常に重要



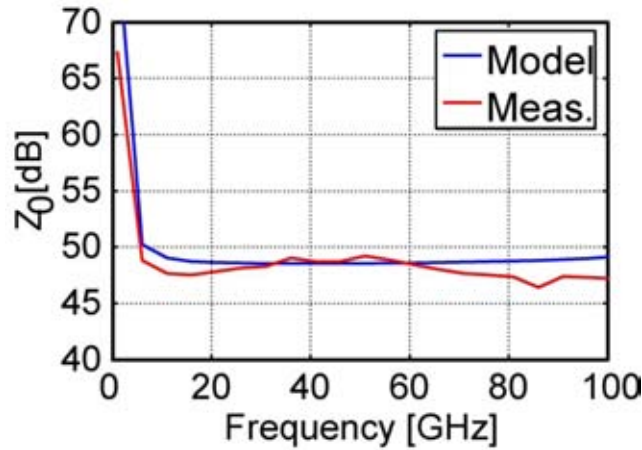
Second T.O.

Second T.O.

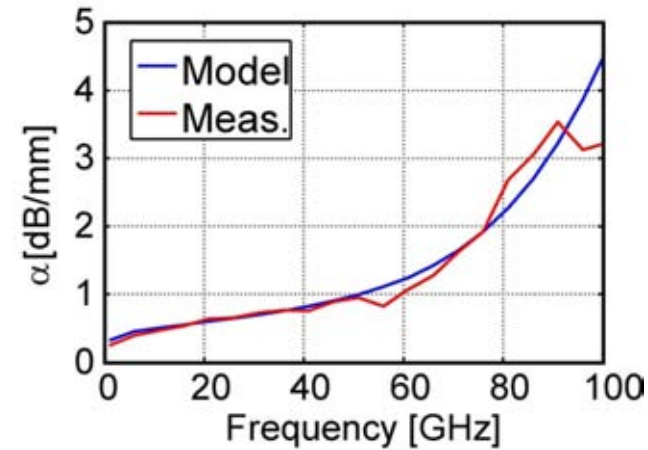
- Circuit building blocks
- Whole system



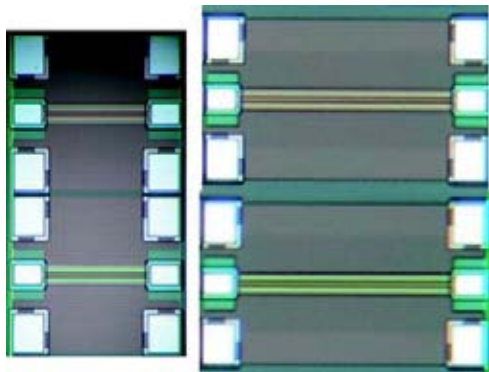
Cross Section



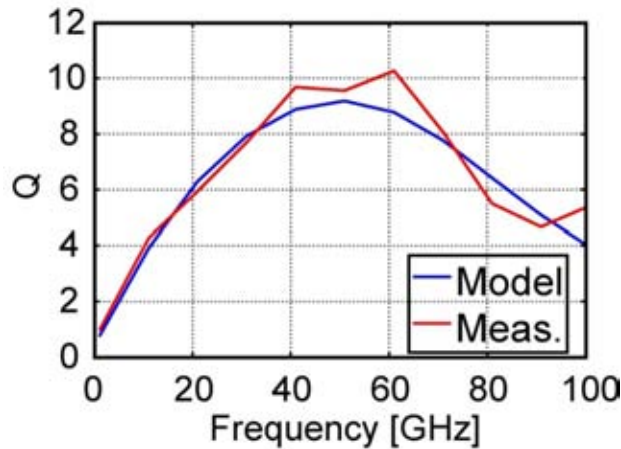
Z_0



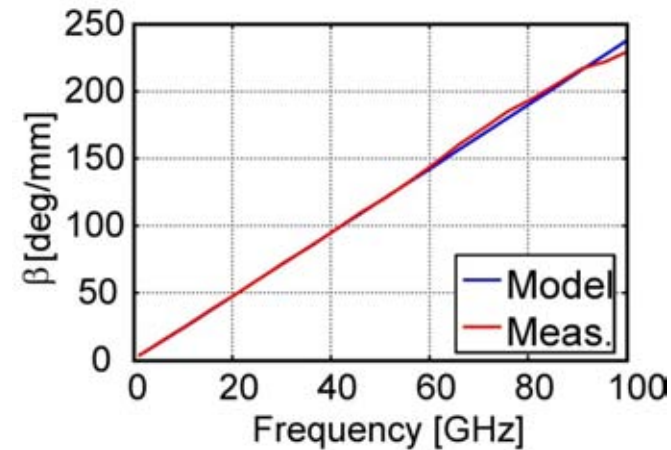
α



Chip photo

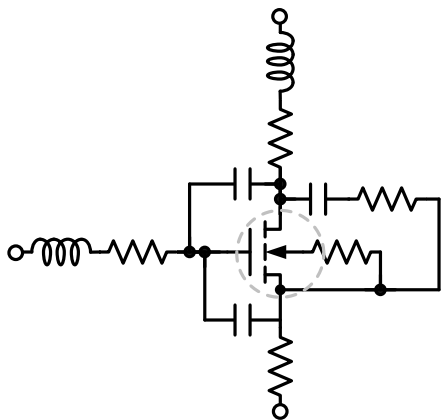


Q

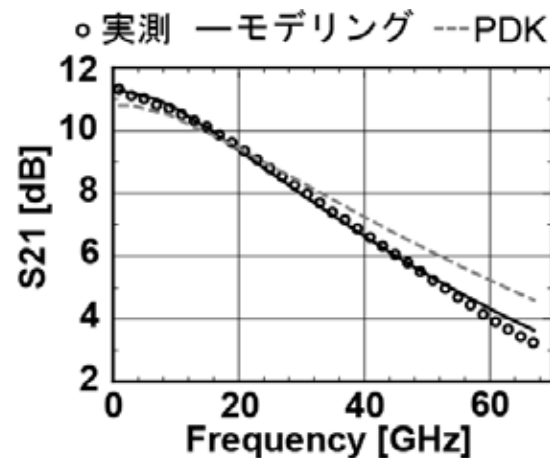


β

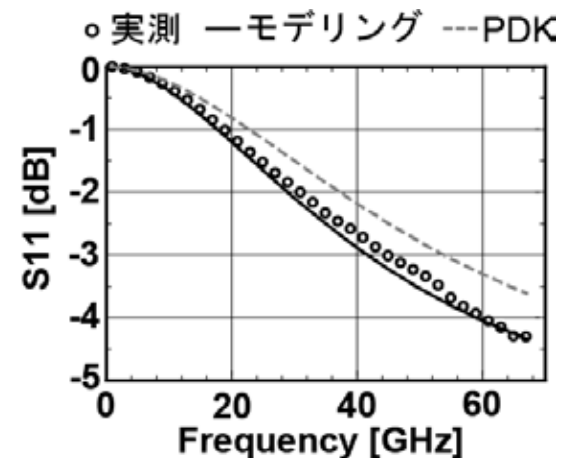
- 寄生成分を付け足し、測定データと合わせる
 - トランジスタの利得
 - 誤差 1 dB \Rightarrow 0.2 dB
 - 反射特性
 - 誤差 0.8 dB \Rightarrow 0.1 dB



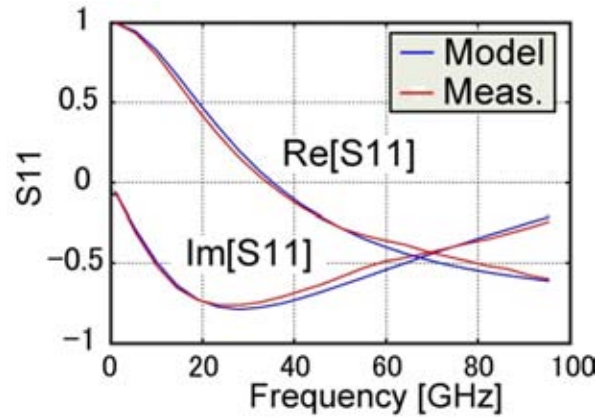
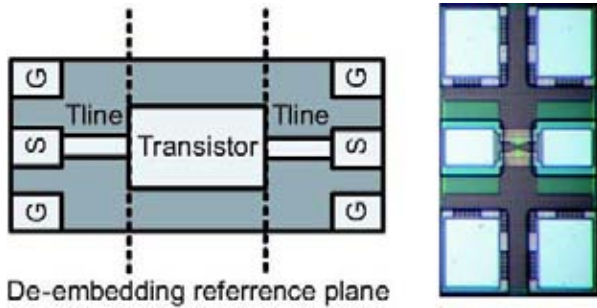
モデル回路



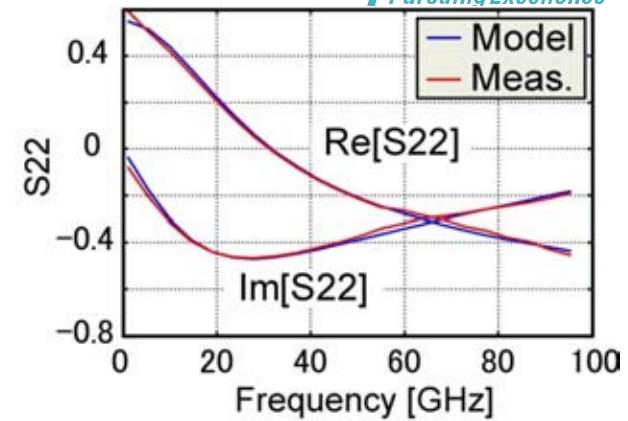
利得特性



反射特性

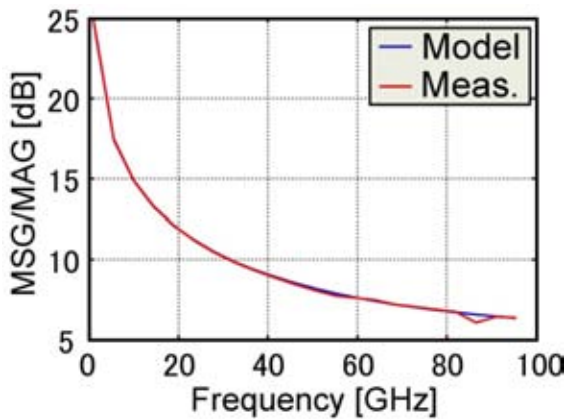


S11

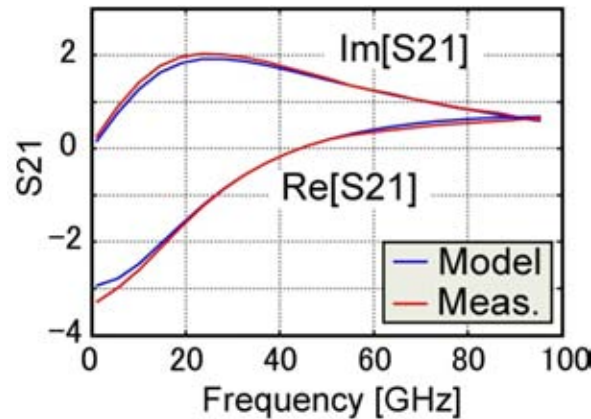


S22

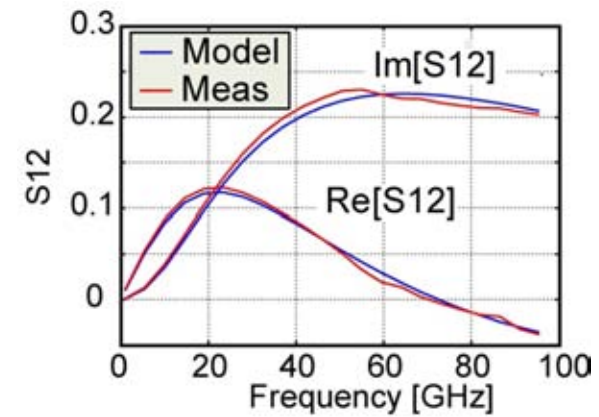
Chip photo



MSG/MAG

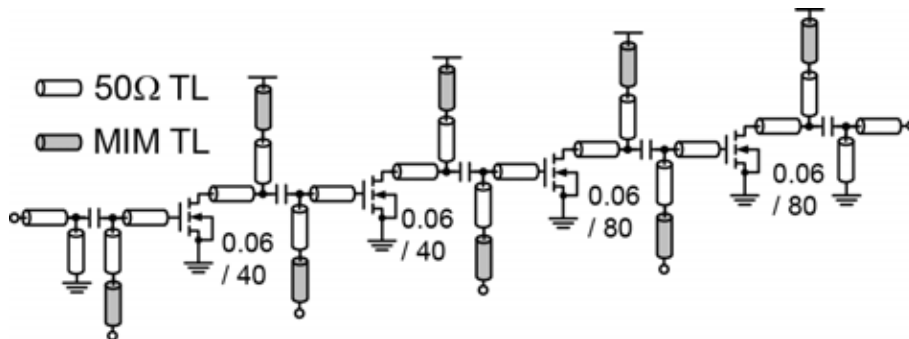


S21

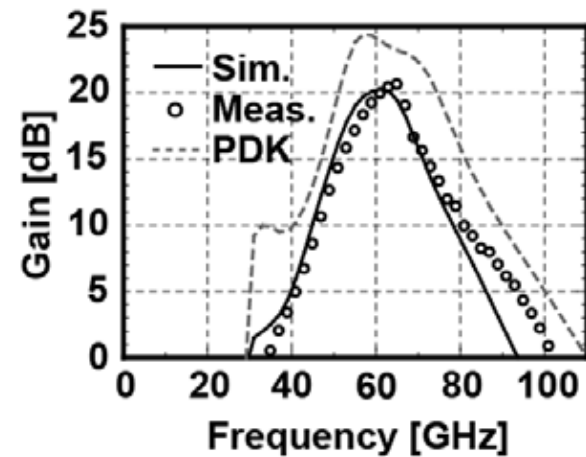


S12

- 回路構成
 - モデリングした各素子を用いて設計
 - 4-stage構成
 - CMOS 65nm
- 測定結果
 - 素子のモデリングにより、シミュレーションの精度が向上
 - Sim.-Meas.誤差 5dB \Rightarrow 0.5dB以下



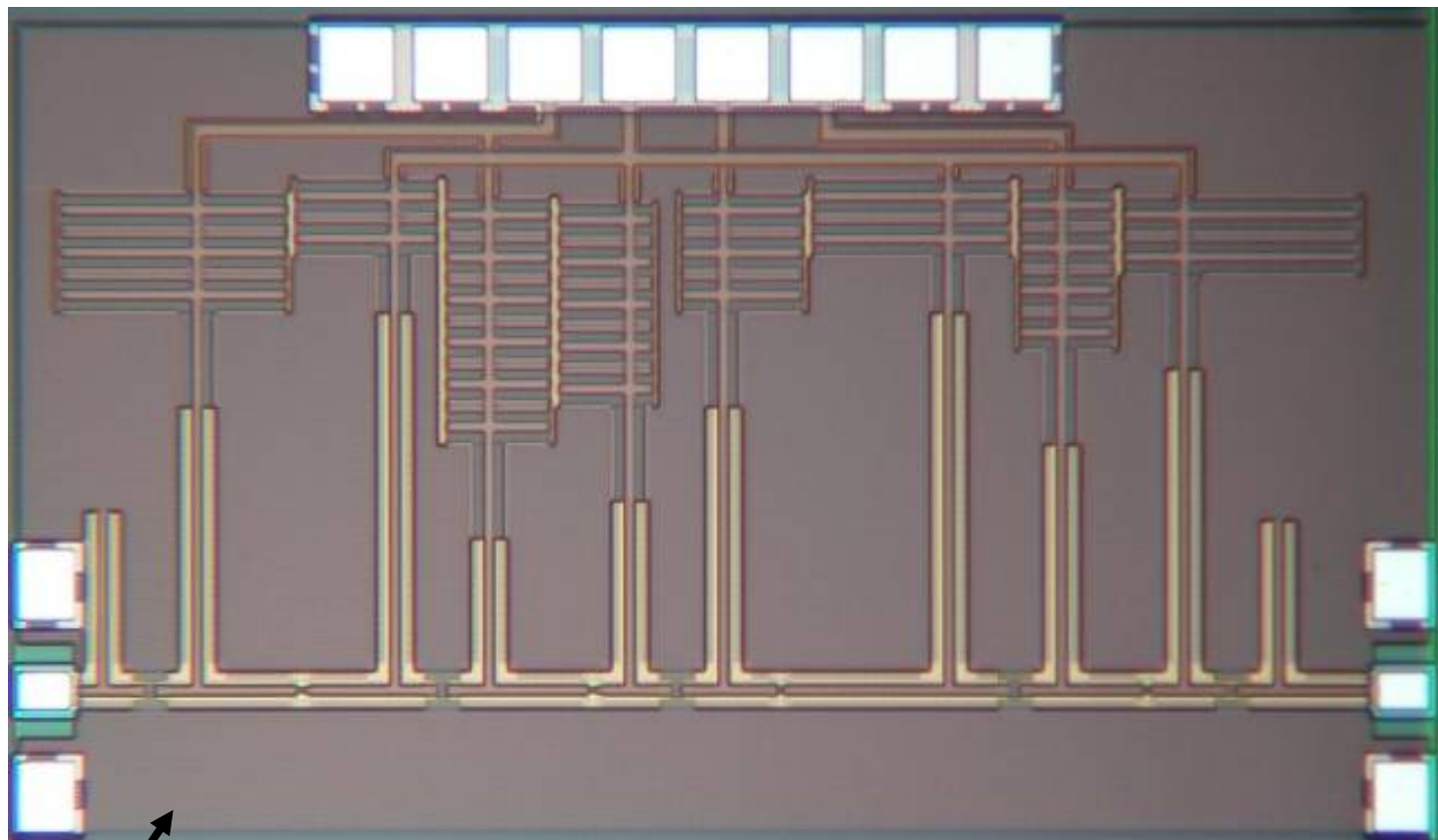
パワーアンプ回路図



回路利得の測定結果

Chip micrograph

60GHz CMOS PA



0.85mm

OUT

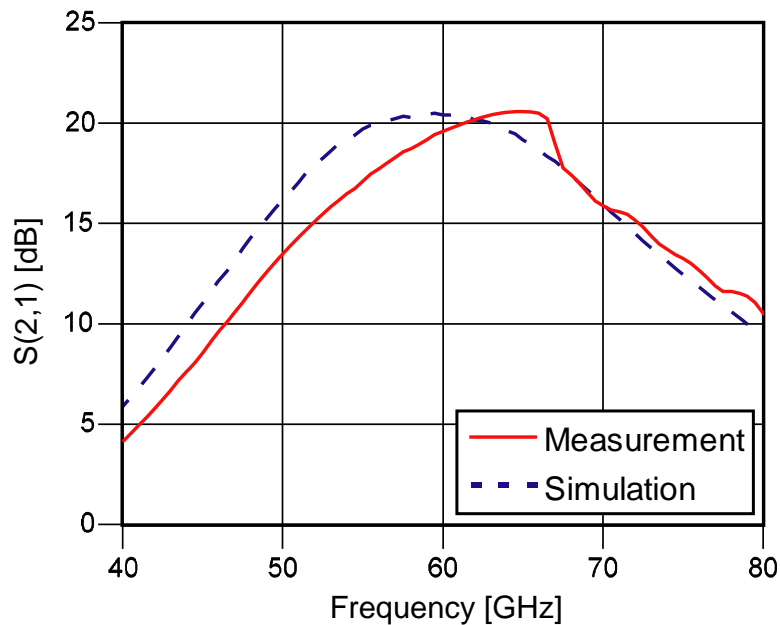
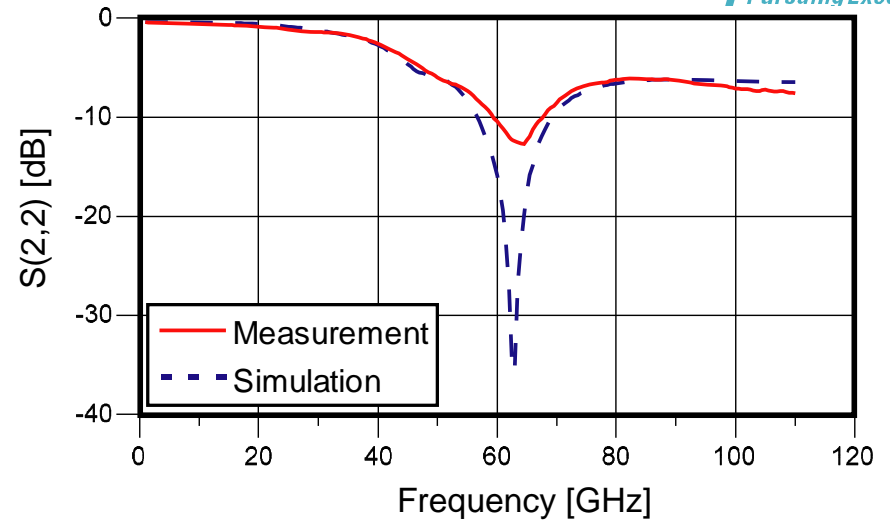
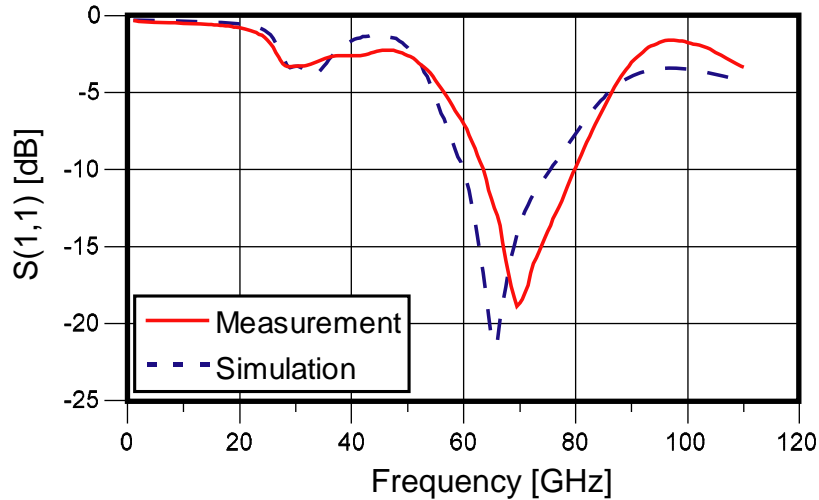
IN

1.5mm

surface ground plane

CMOS 65nm process

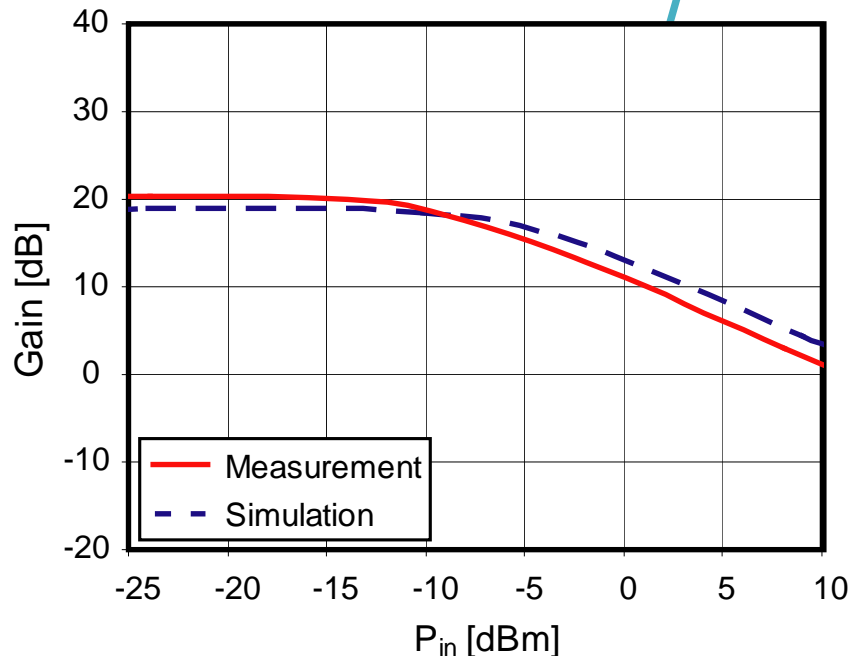
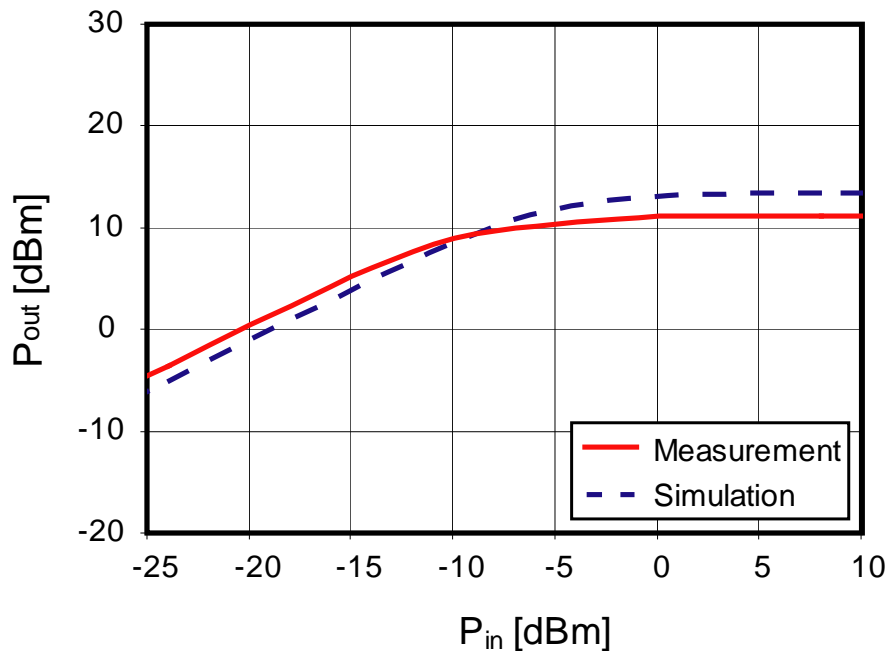
Measurement results



@61.5GHz
 S_{21} : >20dB
 S_{22} : <-10dB

Measurement results

28



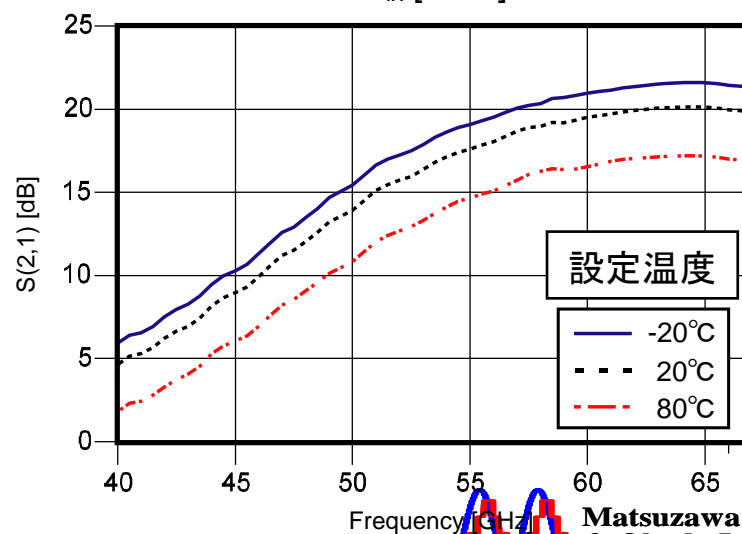
@61.5GHz

PG: 20.4dB

P_{1dB} : 9.9dBm

P_{sat} : 11.1dBm

P_{DC} : 144mW @ P_{1dB}



設定温度

— -20°C
- - 20°C
- - 80°C

Measurement summary

Reference	Technology	Freq. [GHz]	Gain [dB]	P_{1dB} [dBm]	PAE@ P_{1dB} [%]	P_{DC} [mW]	V_{DD} [V]
[4] JSSCC 2007	90nm CMOS	61	5.2	6.4	7.4	21	1.5
[5] RFIC 2008	90nm CMOS	63	14	11	15	81	1.2
[6] ISSCC 2008	90nm CMOS	60	8.2	8.2	2.4	229	1.2
[7] ISSCC 2008	90nm CMOS	60	5.5	9	6	80	1
[8] ISSCC 2008	90nm CMOS	60	13.3	10.5	8	150	1
[9] ISSCC 2009	65nm CMOS	60	15.8	2.5	3.95	43.5	1
[10] ISSCC 2009	45nm CMOS	60	13.8	11	-	-	1.1
[11] MWCL 2009	90nm CMOS	60	30	10.3	6	178	1.8
This work	65nm CMOS	61.5	20	9.9	6.7	144	1.2

[4] T.Yao, *et al.*, JSSC 2007(Tronto Univ.) [5] T.L.Rocca, *et al.*, RFIC 2008 (UCLA) [6] T.Suzuki, *et al.*, ISSCC 2008 (Fujitsu)
[7] D. Chowdhury, *et al.*, ISSCC 2008 (UCB) [8] M. Tanomura, *et al.*, ISSCC 2008 (NEC)
[9] W.L. Chan, *et al.*, ISSCC 2009 (Delft Univ.) [10] K. Raczowski, *et al.*, ISSCC 2009 (KU Leuven&IMEC)
[11] J.-L.Kuo, *et al.*, MWCL 2009 (NTU)

- **伝送線路によるマッチング**
寄生素子の排除
- **タイルベースレイアウト**
厳密にレイアウトとモデルを一致させる
- **実測に基づくIn-house PDK**
ADS提供モデルを流用
ただし、レイアウト依存・周波数依存は、
Heuristicにモデル化